



Inverted Metallurgical Microscopes ECLIPSE MA200/MA100N

ECLIPSE MA200 MA100N

Inverted Metallurgical Microscopes



ECLIPSE

MA200 / MA100N

Features



MA200

Offers high stability, durability, and a smaller footprint than conventional models, as well as easy access to the stage handle, the nosepiece, the BF/DF change lever, and diaphragms, all located on the front side.



MA100N

Designated for brightfield and simple polarizing observation, the MA100 is a cost-effective solution to manufacturing and QA/QC situations in industries such as automotive/electronic parts and industrial machinery/tools.

Compatible observation methods	Brightfield	Darkfield	Simple polarizing	DIC	Fluorescence
	○	○	○	○	—
Compatible illuminators	<ul style="list-style-type: none">LV-LH50PC 12V50W Halogen Lamp IlluminatorLV-LL LED Lamphouse				
Magnification module	<ul style="list-style-type: none">1x/1.5x/2x				
Compatible stages	<ul style="list-style-type: none">MA2-SR Mechanical Stage (stroke: 50 x 50 mm)				

Brightfield	Darkfield	Simple polarizing	DIC	Fluorescence
○	—	○	—	—

*Dedicated reflected illumination models.

- High-intensity white LED Illuminator (internal power supply)

- MA-SR-N Rectangular 3-plate Stage N (stroke: 50 x 50 mm)
 - MA-SP-N Plain Stage N
 - TS2-S- SM Mechanical Stage (stroke: 126 x 78 mm)
- *Please use in combination with MA-SP-N Plain stage N.

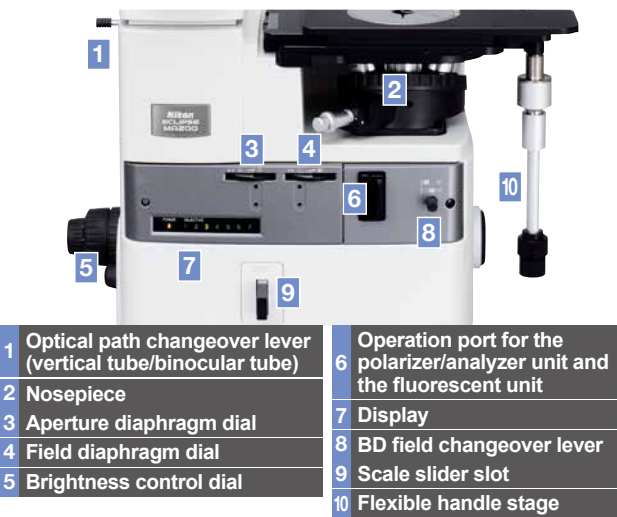
ECLIPSE MA200

An ideal inverted microscope
offered only by Nikon



Front Operation

Delivers ease-of-use by placing all important controls at the front of MA200N.



Quick Status Check



Automatically detects the address of the objective lens currently in use and displays it on the main unit front panel.

The observation position of the objective lens and sample can be checked easily from the microscope's front panel.

Box Structure

The unique box structure is 1/3 smaller than conventional models and offers improved durability.

Compact structure with a depth of 315 mm

A box shaped microscope, not only the width but also the depth is reduced dramatically: The foot print is only one-third of the conventional model!

High stability and durability

Reduced vibration during high-power observation, offering a highly rigid microscope.

Evolved Optical Performance

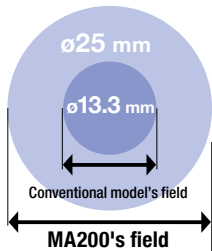
Provides a more ergonomic observation with clearer images.

Super-wide field of view

A sample with a diameter of just 25 mm can be observed in an one field of view by combining the ultra wide field of view eyepiece and 1x objective lens.



• T Plan EPI 1x
Wide field of view

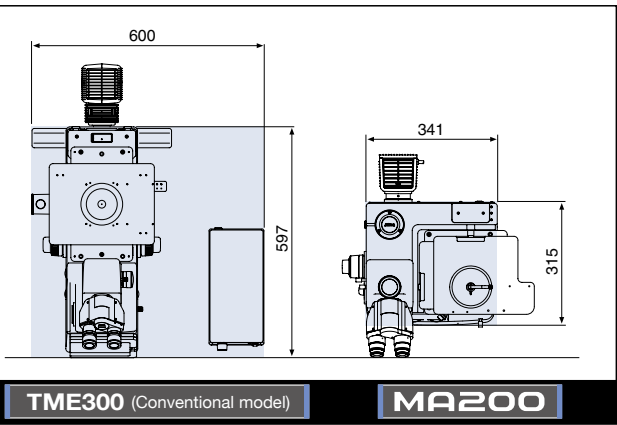


Even Illumination

Improved uniformity of illumination delivers clear images, especially for digital imaging.

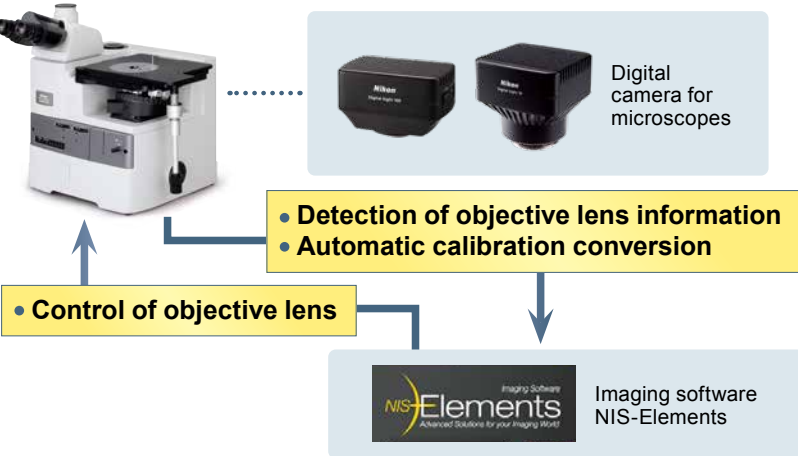
Combine images with the stitching feature

Can combine up to eight images with uniform lighting and no seams.



Combination with Digital Camera

The MA200 allows detection of information and control of objective lenses, enabling optimization of the conditions vital for image acquisition.



Note: Information detection and control of accessories are not available with NIS-Elements LE, L, and F. Please use NIS-Elements D for these functions.

Illumination

Expanded lineup

Added a compact LED illuminator to the existing lineup. With the use of LED, Nikon illuminators are power saving and achieve long life.



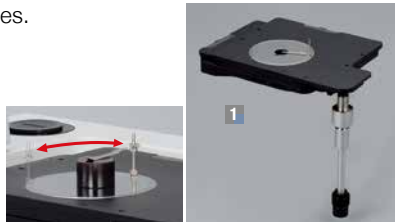
LV-LL LED Lamphouse

Accessories

Stage

Samples can be rotated by the stage clip. The stage delivers high durability needed to support heavy samples.

1 MA-2 SR Stage



DIC Units

Standard and high contrast type DIC prism are available to match needs of the sample.

These prisms are effective for observation of minute step heights.

1 MA2-PA Unit 2 L-DIHC DIC Prism (High Contrast)
3 L-DIC DIC Prism



Nosepiece & Magnification Module

Enables communication of objective lens position, magnification and intermediate magnification module information with the NIS-Elements image software.

1 MA2-MC Magnification Module
2 LV-NU51N Nosepiece



Holders

A full lineup is available that correspond to a variety of sample shapes.



Polarizing Units

Polarizing observation is effective for birefringence samples. MA2-PA unit is suitable for observation of aluminium.

• Single-action operation • Aluminium sample
Links the attachment/release of the analyzer/polarizer.

1 MA2-PA Unit
2 MA2-UPA Unit*
3 MA2-λ P λ Plate

*It is suitable for inspecting aluminium sample.



Grain Size Reticle & Scale

Overlays a pattern onto the observed image. The Grain Size Reticle is used for grain size analysis and complies with the JIS G0551 and ASTM E112 standards. The Scale displays a scale for each objective lens magnification.

1 MA2-GR Grain Size Reticle JIS G0551/objective lense 10x (100× magnification)
ASTM E112/objective lense 10x (100× magnification)
2 MA2-MR Scale



ECLIPSE MA100N

A durable, user-friendly Inverted Microscope with superior image quality, a small footprint and great cost performance.



Illumination

Employment of high-intensity LED illumination (Eco-illumination)

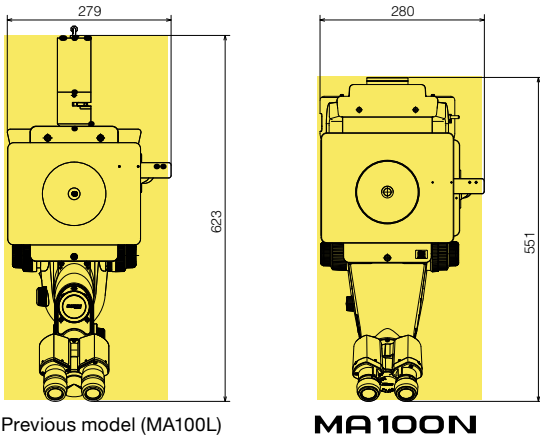
Compared to conventional halogen illumination, these high intensity LED sources need only about one third of consuming electricity and last approximately 30 times longer. The MA100N ensures stable sample observation with uniform color temperature even in different light intensity.



Compact Body

Redesigned to be smaller

Designed for LED illumination, the footprint is 11% smaller than conventional models, allowing users to have more installation choices.



Stage

Controlled stability even with heavy samples/ Boasts superior durability

The MA-SR-N Rectangular Stage was developed especially for the MA100N. The three-plate structure allows for observation of heavy samples, such as a grinder resin mounted samples.



Aperture Diaphragm

Standard with MA100N

The epi illuminator comes standard with a variable aperture diaphragm to control image contrast and depth of field.



Accessories



Basic stage set

A triple-platform stage structure lets you use heavy samples.

- 1 MA-SR-N Rectangular Stage N
- 2 Specimen Holder (ø20/30/40 mm aperture)
- 3 MA-SH3 Specimen Holder 3
- 4 MA-SRSH1 Universal Specimen Holder



Grain size reticle

The class of grain size in a sample can be easily distinguished while observing its image.

- 1 MA100-EPRGS Grain Size Reticle



Digital Camera

Redesigned with optical systems suitable for sample observations. The camera port is located on the side of MA100N to provide improved visibility of the stage.

- 1 Microscope Camera Digital Sight 100
- 2 C-0.63x-TS2 C-mount Adapter
- 3 TS2-P-CF Camera port 100



Other accessories

- 1 TI-SM Mechanical Stage CH
- 2 MA-SP-N Plain Stage N
- 3 MA-SH2-N Specimen Holder 2N
- 4 MA-S-HU Universal Holder
- 5 MA-SH3 Specimen Holder 3
- 6 MA-SRSH 25-40 Holder
- 7 MA-SRSH1 Universal Specimen Holder
- 8 MA-SH1-N Specimen Holder 1N
- 9 MA-P/A Simple Polarizer



CFI60-2

Nikon's CFI60 optical systems are highly evaluated for their unique concept of high NA combined with a long working distance. These lenses have been developed further and evolved achieving the apex in long working distance specifications, correct chromatic aberration, and an optimized lens weight.

Standard objective lenses

TU Plan Fluor Series

EPI/BD 5x/10x/20x/50x/100x

Enable brightfield, darkfield, simple polarizing, sensitive polarizing, differential interference, and epi-fluorescence observations with just one lens. Achieves superior chromatic aberration performance with long working distance for all magnifications to adapt to any application.

Long WD

Semi-apo

Light weight

Fly-eye lens



*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance(mm)
TU Plan Fluor EPI (brightfield type)	5x	0.15	23.5
	10x	0.30	17.5
	20x	0.45	4.5
	50x	0.80	1.0
TU Plan Fluor BD (brightfield/ darkfield type)	100x	0.90	1.0
	5x	0.15	18.0
	10x	0.30	15.0
	20x	0.45	4.5
	50x	0.80	1.0
	100x	0.90	1.0

Long working distance objective lenses

TU Plan ELWD Series

EPI/BD 20x/50x/100x

With the phase Fresnel lenses, these objective lenses enable long working distances while offering higher level chromatic aberration correction than conventional objective lenses. This improves operability for samples with different heights.

Long WD

Semi-apo

Light weight

*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance(mm)
TU Plan EPI ELWD (brightfield type)	20x	0.4	19.0
	50x	0.6	11.0
	100x	0.8	4.5
TU Plan BD ELWD (brightfield/ darkfield type)	20x	0.4	19.0
	50x	0.6	11.0
	100x	0.8	4.5

Low-magnification objective lenses

T Plan EPI

EPI 1x/2.5x

Both clear observation using a conventional analyzer/polarizer and operability-oriented observation without the need of an analyzer/polarizer are possible.

Wide field of view

Model	Magnification	NA	Working Distance(mm)
T Plan EPI (brightfield type)	1x	0.03	3.8
	2.5x	0.075	6.5

Apochromatic objective lenses

TU Plan Apo series

EPI/BD 50x/100x/150x

By using phase Fresnel lenses, these objective lenses achieve significantly longer operating distances while maintaining the superior chromatic aberration performance of apochromatic lenses.

Long WD

Apo

Light weight

*Brightfield observation (EPI) objective lens

Model	Magnification	NA	Working Distance(mm)
TU Plan Apo EPI (brightfield type)	50x	0.8	2.0
	100x	0.9	2.0
	150x	0.9	1.5
TU Plan Apo BD (brightfield/ darkfield type)	50x	0.8	2.0
	100x	0.9	2.0
	150x	0.9	1.5

Other Lenses

Brightfield objective lens

CFI L Plan EPI 40x

A 40x objective lens is best for metal analysis.

NA: 0.65 W.D.: 1.0 mm

Digital camera system for microscopes **DIGITAL SIGHT SERIES**

Microscope camera

Digital Sight 1000

Equipped with a 2 megapixel CMOS image sensor, it can capture full HD microscope images. By connecting a microscope to this camera and HDMI monitor, movies and images can be captured and saved onto a pre-inserted SD card in the camera.

2.0 megapixel

Color

C mount

Digital Sight 100

Combined with industrial microscopes, the camera delivers 6.5-megapixel resolution (2944x2208 pixels). HDMI monitor output enables on-site observation without a PC.

6.5 megapixel

Color

C mount

Digital Sight 10

This high-resolution camera captures both color and monochromatic images at up to 6,000 x 3,984 pixels. This enables the wide range of images to be captured and then many of them to be stitched together making a single and large combined image.

23.9 megapixel

Color/Mono-chrome

F mount

Max Frame Rate	30 fps (1920x1080)	60 fps (1600x900)	55 fps (2000x1328)
Max Recordable Pixels	1920x1080	2944x2208	6000x3984

*Digital Sight 100, standalone, delivers up to 17.7-megapixel resolution (4864 x 3648 pixels).

Imaging software NIS-Elements

Using a desktop PC

Using a desktop PC / tablet PC

Image Stitching

Stitches together images acquired from multiple fields of view to create one image.

EDF (Extended Depth of Focus)

Create a single, all-in-focus image from images of differing focus.

A wide variety of tools

Enables the conducting of simple measurements on images, with input of lines and comments. These can also be written onto and saved with the image, and measurement data can be output.

Measurement function

Annotate function

Scene Mode

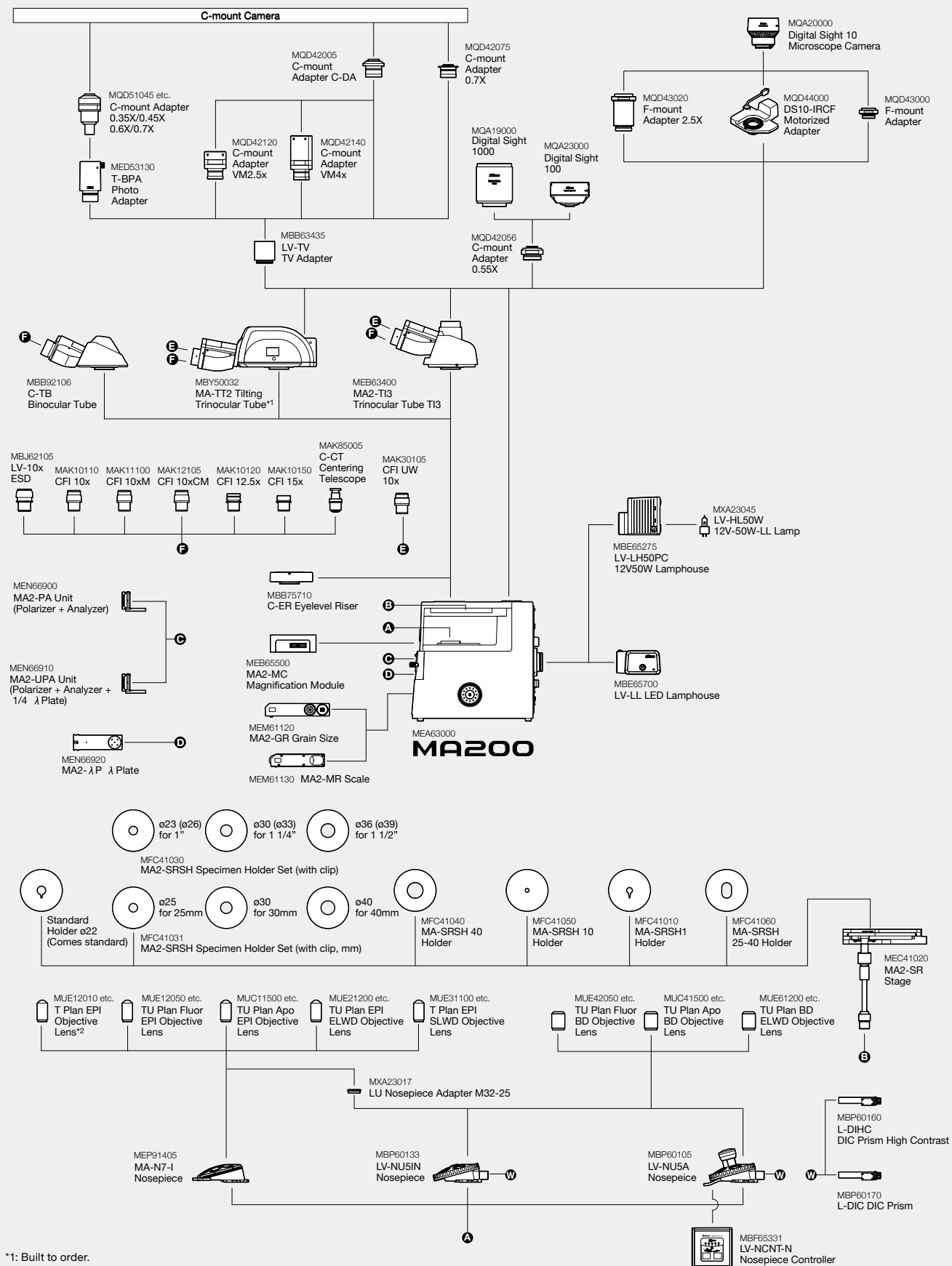
Ten camera setting patterns for optimal color reproduction and contrast for each microscope light source, observation method and type of sample, as well as custom settings, can be selected.

Information detection and control of accessories are not available with NIS-Elements LE, L, and F. Please use NIS-Elements D for these functions.

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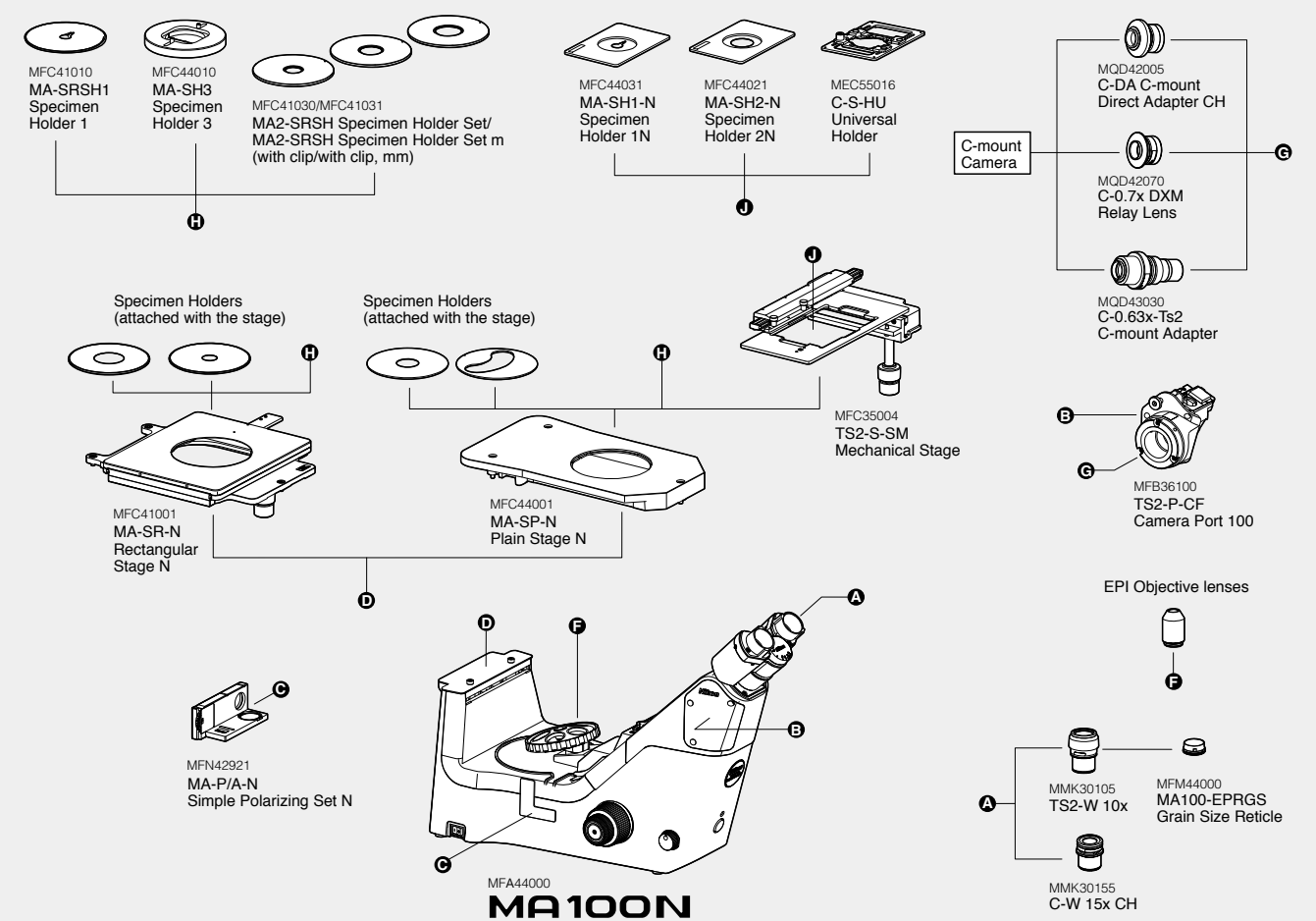
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System Diagram (MA200)

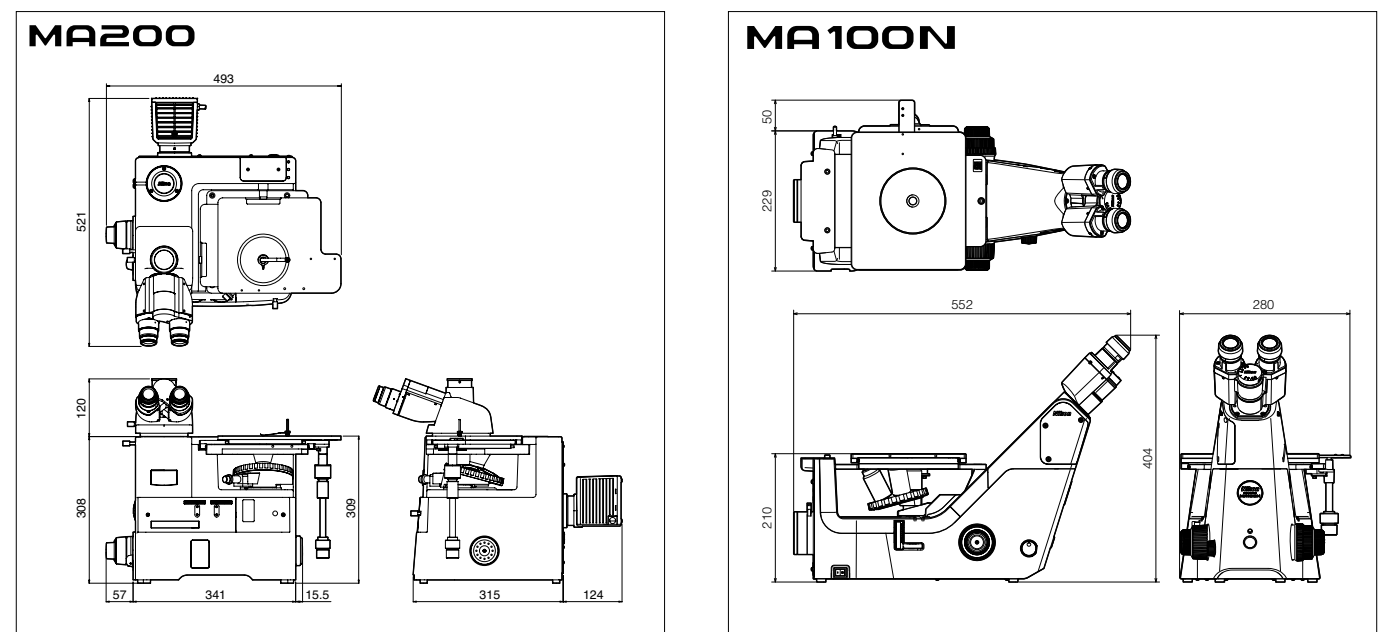


*2: T Plan EPI 1x/2.5x enable clear observation using a conventional analyzer/polarizer, as well as operability-oriented observation without need for an analyzer/polarizer.

System Diagram (MA100N)



Dimensions



Specifications (MA200)

MA200	
Main body	Focusing mechanism Focusing nosepiece (Fixed stage) Coaxial coarse/fine adjustment knob (torque adjustable) Coarse adjustment of 4.0 mm per rotation, fine adjustment of 0.1 mm per rotation
	Illumination With flare prevention, Built in UV cut filter Field diaphragm: dialing continuous variable (centerable), Aperture diaphragm: dialing continuous variable (centerable) Polarizing block (Selectable with or without 1/4 λ Plate) 12V50W Halogen Lamp, LV-LL LED Lamphouse
	Light distribution Eyepiece tube/Back port: 100/0, 55/45
	Optics CFI60/CFI60-2 system
Observation image	Surface Image
Observation method	Bright/Darkfield/Simple Polarizing/DIC
Revolving nosepieces	LV-NU5IN: Bright/Darkfield/DIC 5 position nosepiece, LV-NU5A: Motorized Bright/Darkfield/DIC 5 position nosepiece MA-N7-I Brightfield 7 position nosepiece (Intelligent)
Stage	MA2-SR Mechanical Stage (X/Y flexible handle) Dimension: 295x215 mm, Stroke: 50 mmx50 mm (with distance graduation), Standard accessory: ø22 universal specimen holder (with sample clip)
Trinocular eyepiece	Siedentopf interpupillary distance adjustment 50-75 mm
Power source	100-240 V, 50-60 Hz
Power consumption (max.)	1.2 A 75 W
Weight	Approx. 26 kg (depends on combination)
Options	Intermediate magnification Turret (1x, 1.5x, 2x), Status detection (Output magnification information to main unit)
	Scale MA2-GR Grain Reticle (ASTM E112-63 grain sizing numbers 1 to 8), Grid Reticle (20 lines, 0.5 mm)
	MA2-MR Scale Reticle (compatible with 5-100x, Read in μ m, Dialing System)

Specifications (MA100N)

MA100N	
Optics	CFI60/CFI60-2 system
Observation image	Reversed image
Observation method	Brightfield and polarization (with MA P/A simple polarizer/analyzer set)
Focusing	Focusing nosepiece (fixed stage), coaxial coarse/fine adjustment knob with 8.5-mm stroke (Coarse adjustment of 37.7 mm per rotation, fine adjustment of 0.2 mm per rotation)
Nosepiece	Brightfield 5-position nosepiece
Stage	MA-SR-N Rectangular 3-plate Stage N: 50x50 mm stroke (includes two stage inserts (ø20 mm and 40 mm opening) and coaxial control handle on the right side) The 3-plate design allows entire top surface to move. Optional Stage inserts: MA-SRSH1 Specimen Holder 1 with (ø15 mm opening or MA-SH3 Specimen Holder 3 with 2 mm to 32 mm adjustable opening) MA-SP-N Plain Stage N: 188x310 mm - Includes two stage inserts (1) clear acrylic stage insert with ø30 mm opening, (2) clear acrylic stage insert with crescent opening (width 30 mm) to allow clearance for rotation of high magnification objectives Optional stage inserts: MA-SRSH1 Specimen Holder 1 with 15 mm opening or MA-SH3 Specimen Holder 3 with 2 mm to 32 mm adjustable opening Accepts Attachable Mechanical Stage TI-SM TS2-S-SM Mechanical Stage: 126 mmx78 mm stroke, handle can be attached on the right or left side of the plain stage Optional Specimen Holders to fit Attachable Mechanical stage: MA-SH1-N Specimen Holder 1N (ø15 mm opening) MA-SH2-N Specimen Holder 2N (ø30 mm opening), or C-S-HU Universal Holder (30 mm to 65 mm adjustable opening)
Illuminator	Internal power supply white LED light source, condenser built-in (lever operated)
Binocular body	Built-in Siedentopf binocular, 45 inclination angle and 50 to 75-mm interpupillary adjustment, attachable camera port, eyepiece/Port: 100/0/0/100
Power consumption (max.)	15W
Weight	Approx. 10 kg

Specifications and equipment are subject to change without any notice or obligation on the part of the manufacturer. December 2025 ©2006-2025 NIKON CORPORATION

N.B. Export of the products* in this brochure is controlled under the Japanese Foreign Exchange and Foreign Trade Law. Appropriate export procedures shall be required in case of export from Japan.

*Products: Hardware and its technical information (including software)



WARNING

TO ENSURE CORRECT USAGE, READ THE CORRESPONDING MANUALS CAREFULLY BEFORE USING THE EQUIPMENT.



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